# DSSD, milestones and other mechanics

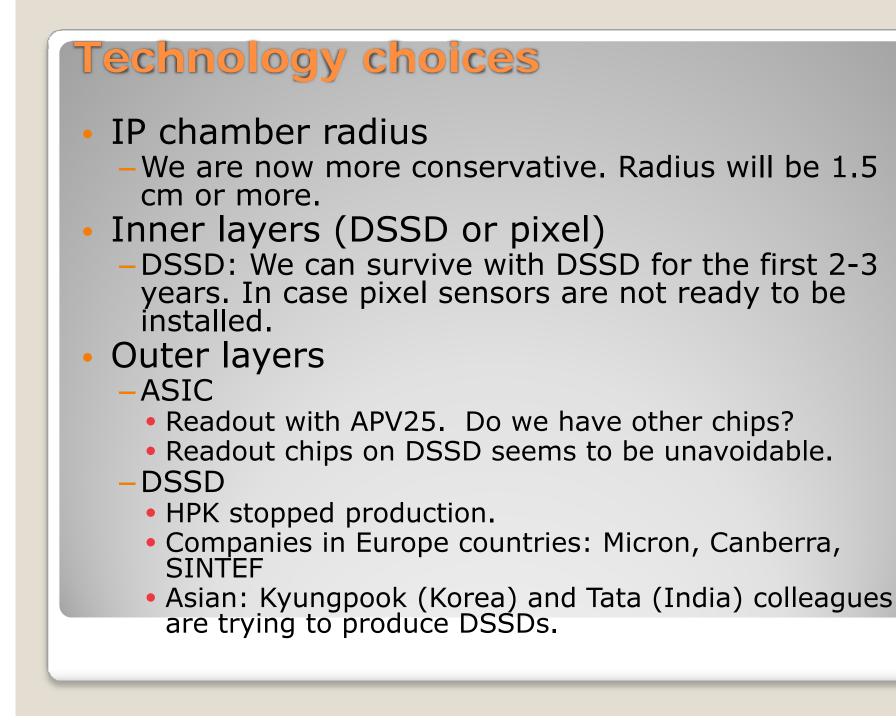
4 July 2008 T. Tsuboyama (KEK)

### LOI design

- The LOI SVD design assumes DSSD sensors from HPK 4" line.
  - Unfortunately, HPK stopped the DSSD production.
- Alternative vendors
  - Micron → Several samples in hands: Not bad. Production from 6" wafers.
  - Kyungpook → DC coupled DSSD was produced. Test in progress.
  - Tata → Waiting for the first test production. Doublesided, double-metal and AC-coupled sensor prototype.

#### Test production by Micron?

- Sensors from 6" wafers are attractive in design of SVD.
- Need to fix the SVD design and DSSD sizes.

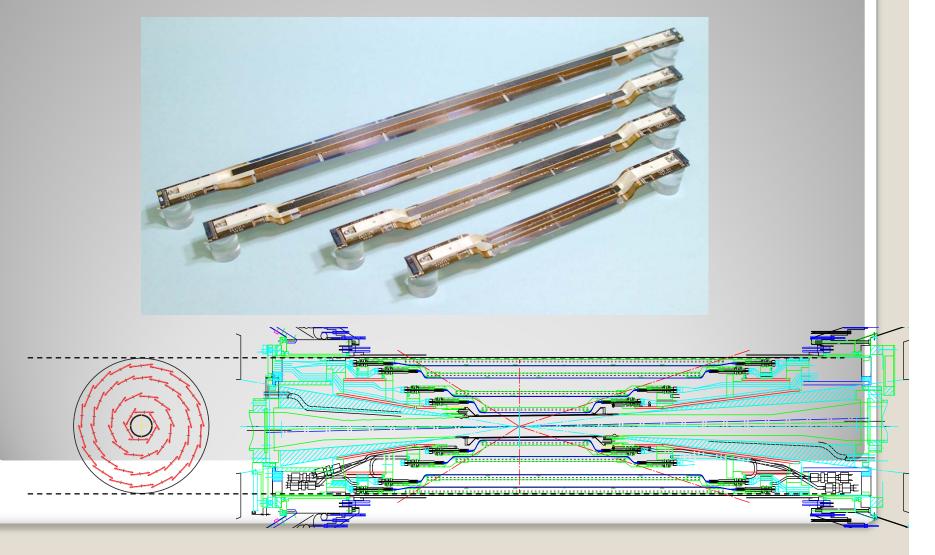


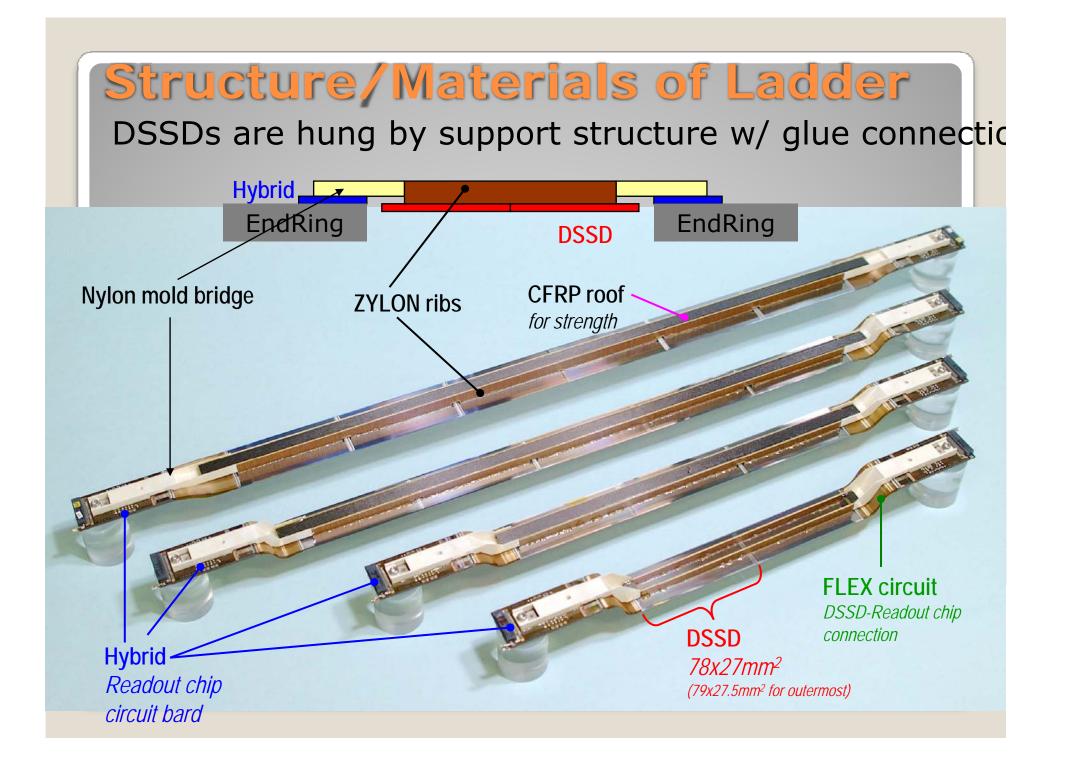
#### Milestones

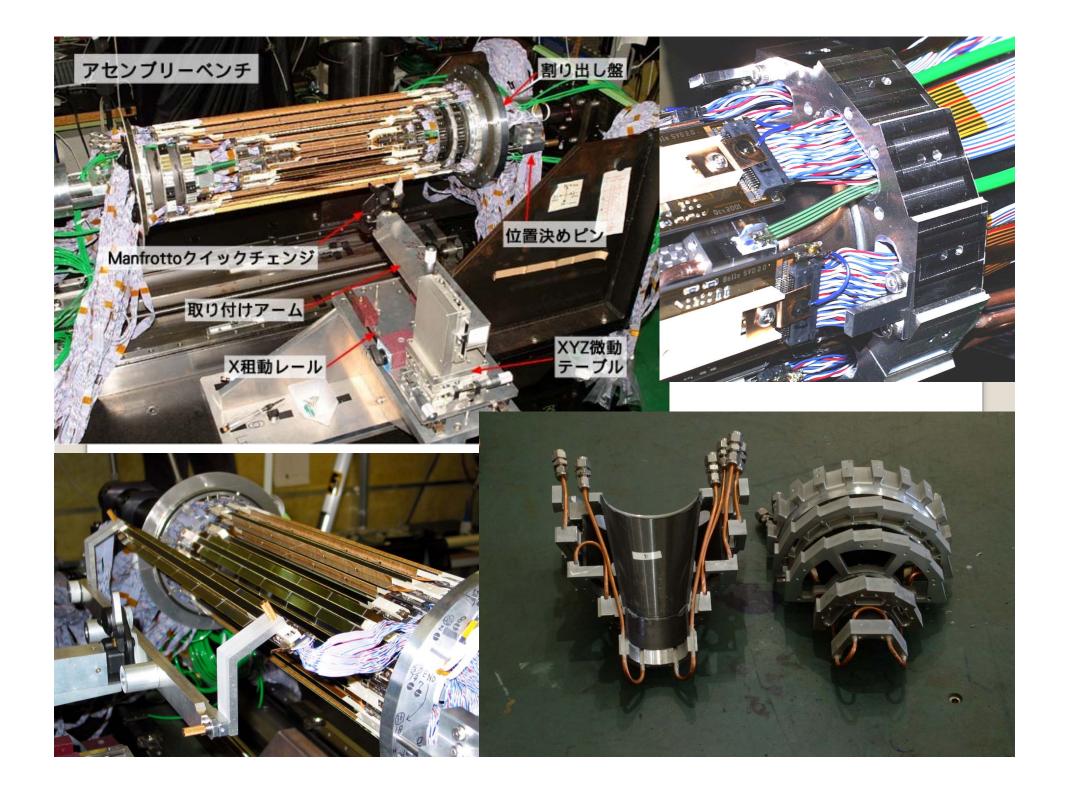
- 2008
  - Demonstrate APV25 readout chain.
    - Design optimization (Osaka, Niigata)
    - Vienna group: APV25 front end, repeater and FADC
    - Cracow group: Data acquisition board (COPPER/FINNESE)
  - DSSD test production
- 2009
  - Fix the design of Silicon vertex detector including pixel.

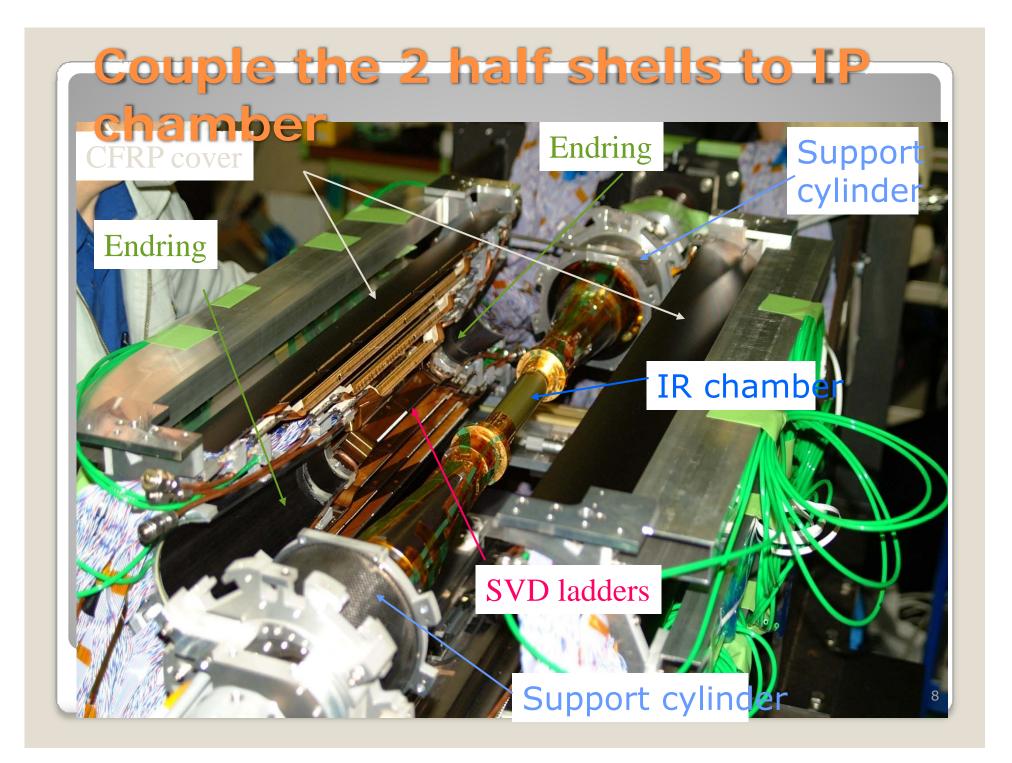
## Ladder structure

#### Unit to realize layer structure using DSSDs



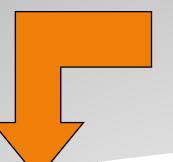


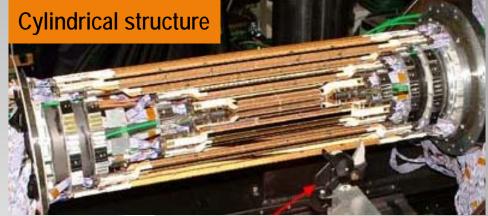


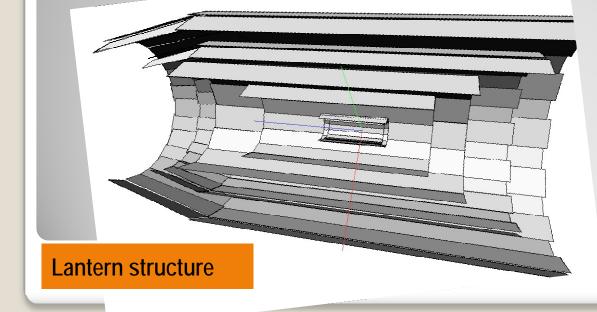


## Ladder layout / mount

ladders were mounted on the endring







Innder four layers are mounted on endring ⇔

Outer two (super-) layers are mounted on the outer cover, then cover will be mounted on the endring

### **Mechanical consideration**

 Can strips and pixels be separated?
Staging/replacement of Pixel detector sometime after the installation.

 What if pixel sensor is mounted on the IP chamber, while strips are mounted on support structure?

